

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:) Confirmation No.: 3788
Shinji MAEKAWA et al.) Examiner: Stanetta D. Isaac
Application No.: 10/575,492) Group Art Unit: 2812
Filed: April 12, 2006)
For: METHOD FOR FORMING WIRING, METHOD)
FOR MANUFACTURING THIN FILM) Date: <u>January 4, 2010</u>
TRANSISTOR AND DROPLET DISCHARGING)
METHOD)

RESPONSE TO FINAL OFFICE ACTION

Mail Stop: RCE

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated October 5, 2009, Applicants respectfully request reconsideration and allowance of the above-identified application based on the following amendments and remarks. A request for continued examination under 37 C.F.R. § 1.114, including the fee set forth by 37 C.F.R. § 1.17(e), is being filed concurrently herewith, for entry and consideration of the following amendments and remarks.